

High Magnetization and High Electrical Resistivity in Soft Magnetic Fe and Fe-alloy Cluster-assemblies Prepared by Impact Deposition

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Soft magnetic Fe-based nanocrystalline films have been widely obtained by either substrate heating during deposition or post-annealing at around 400-800°C to nanocrystallize amorphous alloy films. Such heat treatments are not appropriate for the magnetic devices and cluster-assembling is a promising alternative to fabricate nano-scale structure-controlled materials. In cluster-assembled films prepared by soft-landing on substrates, however, the initial cluster sizes are maintained, but their stackings are very porous. A low density Fe cluster assemblies (about 30% of the bulk) reveals large coercivity and low saturation magnetization [1]. Here, we report that high-density Fe cluster-assembled films with soft magnetic behaviors can be obtained at room temperature by impact deposition of Fe clusters.

Fe cluster-assembled films were prepared by using the plasma-gas-condensation (PGC)-type cluster beam deposition apparatus [2], which is based on plasma-glow-discharge vaporization (sputtering) and inert gas condensation techniques [3]. The apparatus is composed of the three main parts: a sputtering chamber, a cluster growth region and a deposition chamber. Using the PGC cluster beam deposition apparatus, size- monodispersed bcc Fe clusters with the mean diameter, d, from 7 to 15 nm and the standard deviation less than 10% of d were produced. Based upon deposition experiments of total and charged Fe clusters, we roughly estimated that there are about 20% positively charged clusters, 20% negatively charged clusters and 60% neutral clusters in the Fe cluster beam. By accelerating these charged Fe clusters and depositing them with neutral clusters from the same cluster source onto a metallic sample holder which can be kept at a voltage V_a up to ± 25 kV in the deposition chamber (10⁻² - 10⁻¹ Pa), high-density Fe cluster-assembled films were produced with roughly maintaining the initial cluster sizes. In this experiment, we applied negative V_a from 0 to -20 kV [3].

As shown in Fig.1, the magnetic coercivity, H_c , rapidly decreases while the magnetization per volume, M_{s_i} monotonically increases in Fe cluster assemblies with increasing in V_a : $M_s = 1.78$ T and $H_c < 80$ A/m at $V_a = -20$ kV. The electrical resistivity of Fe cluster assemblies, ρ , is so high as about $20 \mu \Omega$ m at $V_a = 0$ V owing to the very porous stacking of Fe clusters, while it is about 1μ Ω m at $V_a = -20$ kV, being one order smaller, but still one order larger than that of bulk Fe metal.



Fig. 1. Magnetization curves of Fe cluster assembled films deposited on negatively biased substrates. d: the mean cluster diameter and V_a : the bias voltage.



Fig. 2. Temperature dependence of electrical resistivity of Fe cluster assembled films deposited on negatively biased substrates. d: the mean cluster diameter and V_a : the bias voltage.

These features are much improved in Fe-Ni cluster assemblies prepared at $V_a = -20$ kV: M_s is about 2 T and ρ about 2 $\mu \Omega m$ in Fe-rich Fe-Ni alloy cluster assemblies.

It is worth to mention the magnetic permeability at room temperature of Fe cluster assemblies in a high frequency region. As shown in Fig.3, the real part, μ ', is larger than 100 up to the frequency range of about 300 MHz.



Fig. 3. Frequency dependence of permeability. μ ' is the real part and μ " the imaginary part.

In dense Fe cluster assemblies, the exchange coupling among Fe clusters are so strong as to overcome the magnetic anisotropy of Fe clusters and their dipole-dipole interaction as discussed by Herzer [4], while the conduction electrons are scattered by the cluster interfaces, giving rise to the soft magnetic character with high magnetization and high electrical resistivity.

References

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